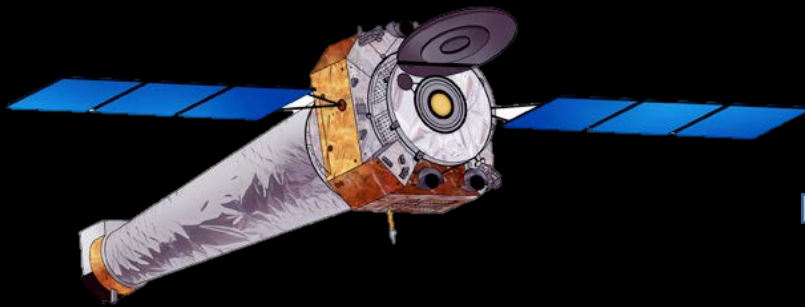
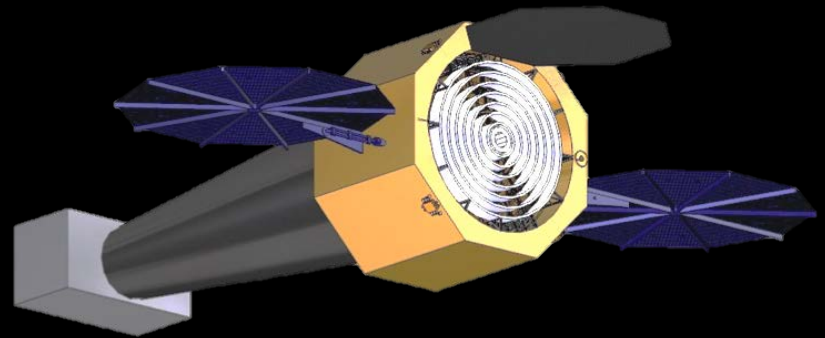


Toward large-area sub-arcsecond x-ray telescopes II



Chandra X-ray Observatory (1999-?)



X-Ray Surveyor concept (~2035?)

Steve O'Dell
NASA Marshall Space Flight Center
and co-authors

Authors represent most of the US effort toward sub-arcsecond x-ray telescopes.

Steve O'Dell ^a, Ryan Allured ^b, Andrew Ames ^b, Michael Biskach ^c, David Broadway ^a,
Ricardo Bruni ^b, Dave Burrows ^d, Jian Cao ^e, Brandon Chalifoux ^f, Kai-Wing Chan ^g,
Yip-Wah Chung ^e, Vincenzo Cotroneo ^b, Ron Elsner ^a, Jessica Gaskin ^a,
Mikhail Gubarev ^a, Ralf Heilmann ^f, Ed Hertz ^b, Tom Jackson ^d, Kiran Kilaru ^h,
Jeff Kolodziejczak ^a, Ryan McClelland ^c, Brian Ramsey ^a, Paul Reid ^b, Raul Riveros ^g,
Jackie Roche ^a, Suzanne Romaine ^b, Timo Saha ⁱ, Mark Schattenburg ^f,
Eric Schwartz ^b, Dan Schwartz ^b, Peter Solly ^c, Susan Troler-McKinstry ^d, Mel Ulmer ^e,
Alexey Vikhlinin ^b, Margeaux Wallace ^d, Xiaoli Wang ^e, David Windt ^j,
Youwei Yao ^{e,f}, Shi Ye ^e, Will Zhang ⁱ, & Heng Zuo ^f

^a NASA Marshall Space Flight Center (USA)

^b Harvard-Smithsonian Center for Astrophysics (USA)

^c Stinger Ghaffarian Technologies, Inc., Goddard Space Flight Center (USA)

^d Pennsylvania State University (USA)

^e Northwestern University (USA)

^f Massachusetts Institute of Technology (USA)

^g University of Maryland Baltimore County, Goddard Space Flight Center (USA)

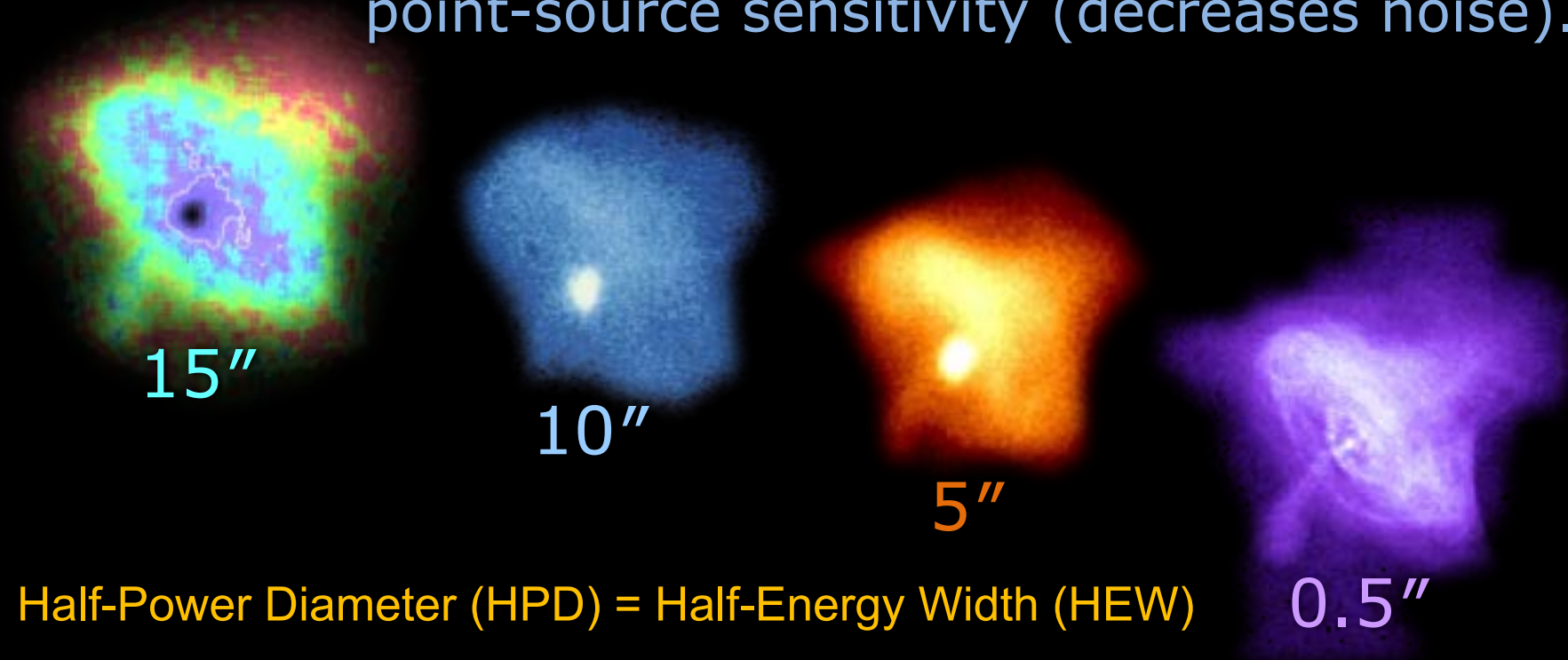
^h Universities Space Research Association, Marshall Space Flight Center (USA)

ⁱ NASA Goddard Space Flight Center (USA)

^j Reflective X-ray Optics LLC (USA)

Key science metrics of an x-ray telescope are angular resolution and aperture area.

Finer angular resolution improves imaging quality and point-source sensitivity (decreases noise).



Larger aperture area improves sensitivity (increases signal), down to angular-resolution confusion limit.

Outline

- Motivation and issues
- Categories of potential solutions
- Post-fabrication corrections

Outline

- Motivation and issues
 - ❑ Seek *Chandra* resolution with $30 \times$ *Chandra* area.
 - ❑ Must resolve both technologic and programmatic challenges.
 - Achieve aperture area and imaging performance within constraints of mass, envelope, cost, and schedule.
- Categories of potential solutions
- Post-fabrication corrections

2020 Decadal Survey in Astronomy and Astrophysics sets priorities for decade.

- National Research Council (NRC) conducts Survey for relevant Government agencies (NASA & NSF).
 - ❑ Addresses space-based and ground-based astronomy.
 - ❑ NASA typically adopts Decadal Survey's priorities.
 - ❑ NASA will suggest space-based astronomy missions.
 - Four Science and Technology Definition Teams (STDT) are developing facility-class mission concepts for NASA.
 - X-Ray Surveyor
 - Far-IR Surveyor
 - LUVOIR Surveyor
 - Habitable Exoplanet Imaging (HabEx)
 - Only one of these is likely to start in the 2020s.
 - Expected launch date would be mid-to-late 2030s.

STDT is defining science-driven requirements for X-Ray Surveyor.

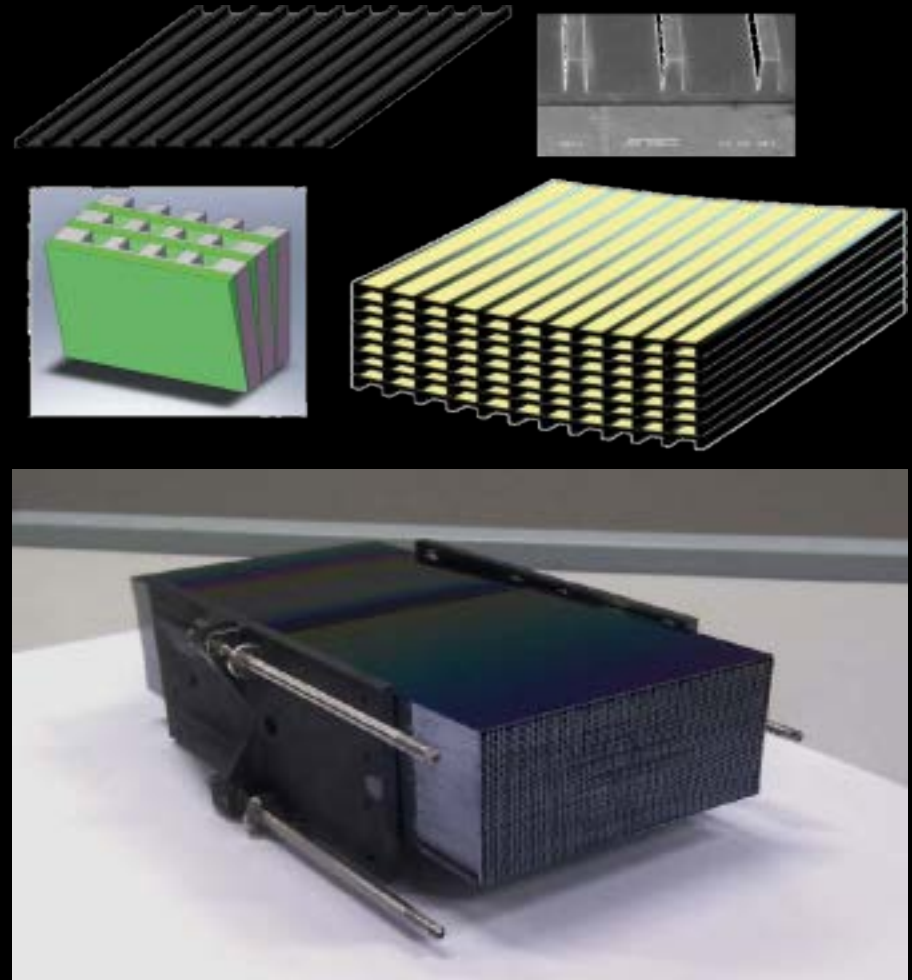
- Anticipate scientific need for an x-ray telescope with *Chandra's* 0.5" resolution and $30 \times$ its area.
- There is general agreement on the top-level technologic and programmatic challenges.
 - ❑ Preserve *Chandra's* angular resolution $\approx 0.5''$ HPD.
 - ❑ Reduce mirror areal mass to *Chandra*/30 $\approx 1.5 \text{ kg/m}^2$.
 - ❑ Reduce mirror areal cost to *Chandra*/30 $\approx 1 \text{ M\$/m}^2$.
- There is not general agreement on how to solve these challenges.
 - ❑ Stiff optics (rigidly supported over-constrained mirrors)
 - ❑ Static optics (fixed, moderately constrained mirrors)
 - ❑ Active optics (adjustable alignment | figure correction)

Outline

- Motivation and issues
- Categories of potential solutions
 - ❑ Stiff optics
 - ❑ Static optics
 - ❑ Active optics
- Post-fabrication corrections

ESA selected ATHENA as its 2nd large-class (L2) mission, for launch in 2028.

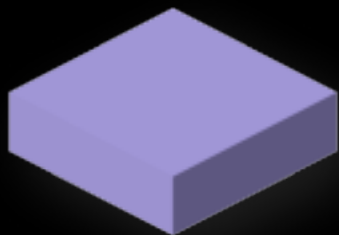
- X-ray mission is in study Phase A, working toward adoption around 2020.
 - ❑ Require HEW $\approx 5''$.
- ATHENA will use stiff, silicon-pore optics (SPO).
 - ❑ Cosine Measurement Systems [NL] leads SPO technology development.
 - Processing and stacking of silicon wafers are highly automated.
 - Resulting rigid x-ray optics units are to be co-aligned.



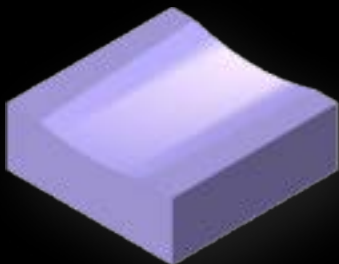
www.the-athena-x-ray-observatory.eu

ESA/ Marcos Bavdaz

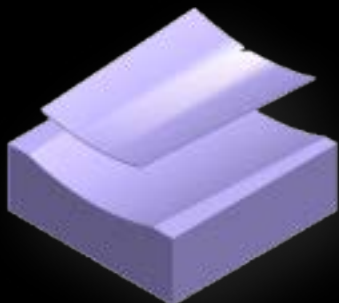
GSFC uses a novel process for light x-ray mirrors of monocrystalline silicon.



1. Procure single crystalline silicon.
2. Heat and chemically etch to remove all surface/subsurface damage.



1. Wire-EDM machine conical shape.
2. Heat and chemically etch to remove damage.
3. Polish to achieve excellent figure and micro-roughness.



1. Use Wire-EDM to slice off the thin mirror segment.
2. Heat and chemically etch to remove all damage from back and edges.

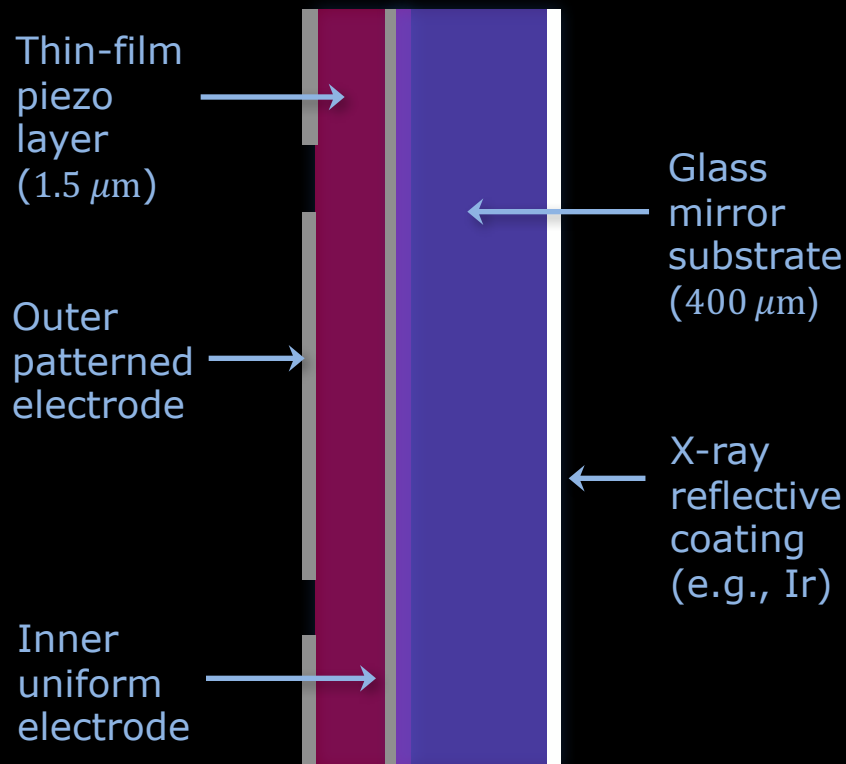
➤ Advantages over glass

- ❑ No internal stress
 - Distortion-free material removal after etching
- ❑ Ideal material properties
 - High thermal conductivity
 - Low thermal expansion
 - High elastic modulus
- ❑ Better performance
 - Made mirrors $< 3''$ HEW₂
 - Aim to build $\sim 1''$ mirror stack by end 2017
 - Aim to build $\sim \geq 1''$ meta-shell by end 2019.

GSFC/ Will Zhang

SAO is developing lightweight active x-ray optics with thin-film piezo arrays.

- Piezoelectric array corrects figure through surface-parallel actuation

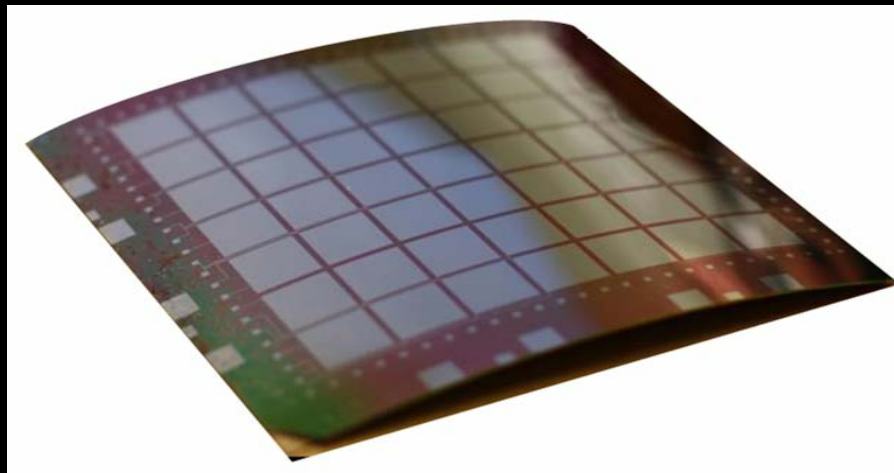


- PSU is fabricating thin-film piezoelectric arrays.
 - ❑ Slumped-glass mirrors from SAO (OAB)
 - ❑ Piezoelectric (PZT) on conductive film, high-T crystallized and annealed
 - ❑ Patterned electrode array with ZnO TFTs
 - Row-column addressing
 - Anisotropic Conductive Film (ACF) connections
 - ❑ Integral T-compensated strain gauges

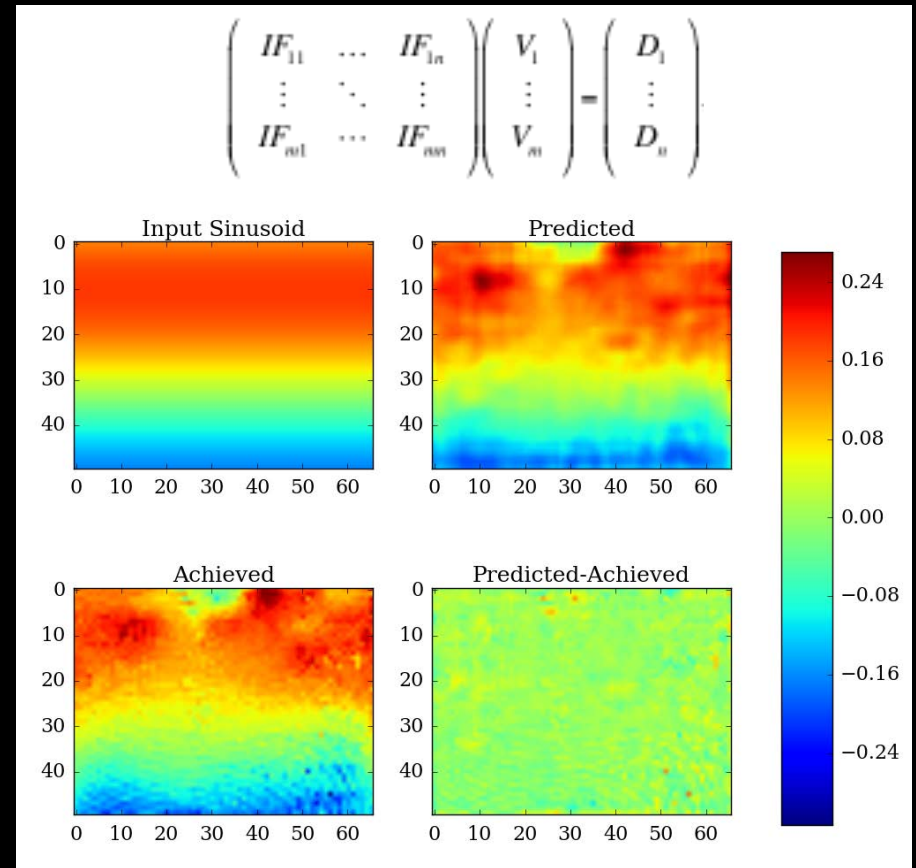
SAO/ Paul Reid

Correction uses calibrated influence functions to determine array voltages.

- Adjustment methodology
 - ❑ Shack-Hartman wavefront sensor metrology
 - Calibrate influence function
 - Measure mirror figure
 - ❑ Calculate and apply voltages for correction



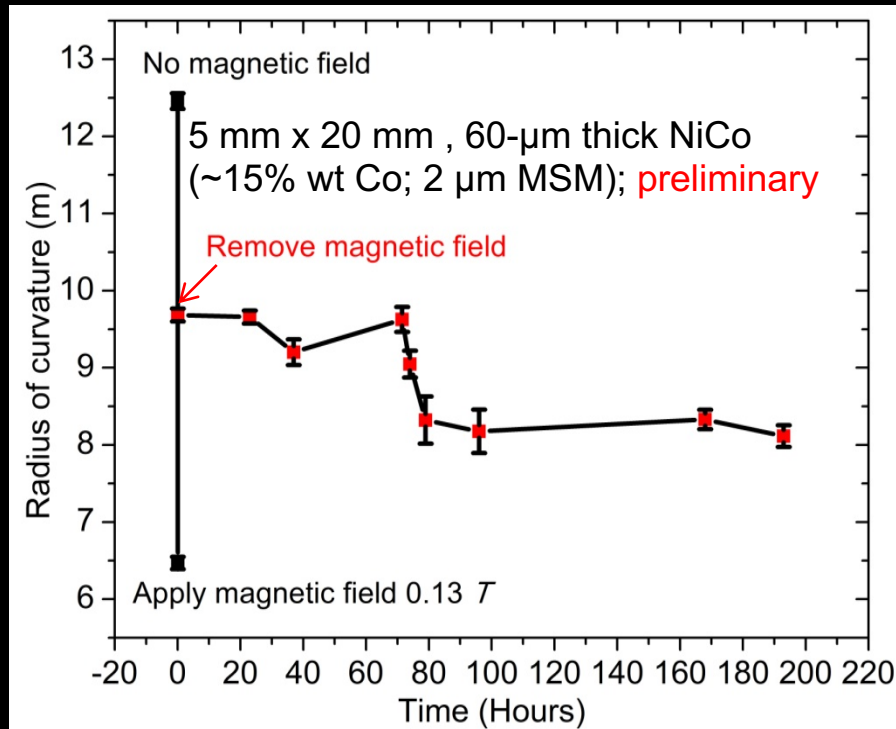
- Correction matrix



SAO/ Ryan Allured

A magnetic smart material MSM provides writable surface-parallel actuation.

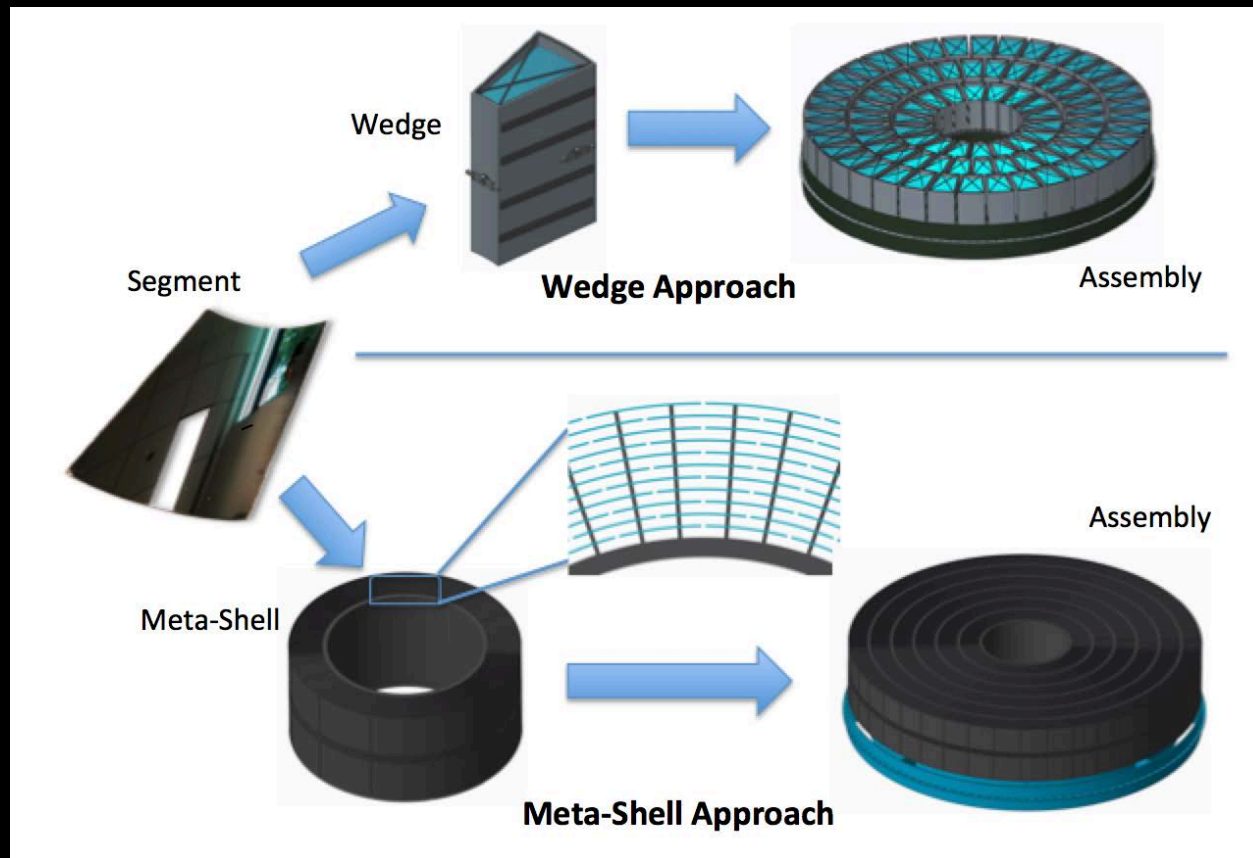
- Use a magnetically hard substrate or coated layer.
- Deposit magnetostrictive (MSM) thin film on back.
- Northwestern Univ. is developing MSM actuators for x-ray optics.
 - ❑ Demonstrated that concept may work.
 - ❑ Must speed up relaxation and stabilization.
 - ❑ Are building models to compare to experiments.
- Can also control coating stress to provide some static figure correction.



NWU/ Mel Ulmer
NWU/ Xiaoli Wang

Synthesize large-area nested Wolter-1-like telescope with aligned segments.

- Few-100-m² surface area in several 1000 segments



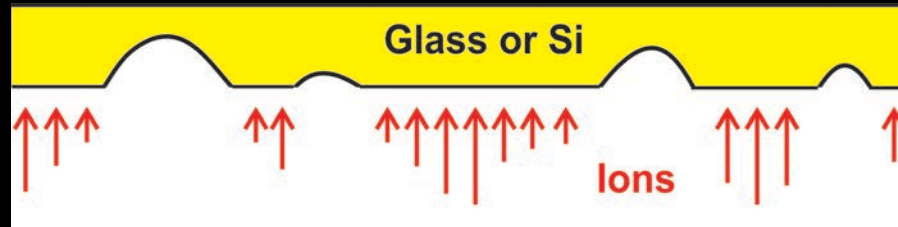
GSFC/ Will Zhang

Outline

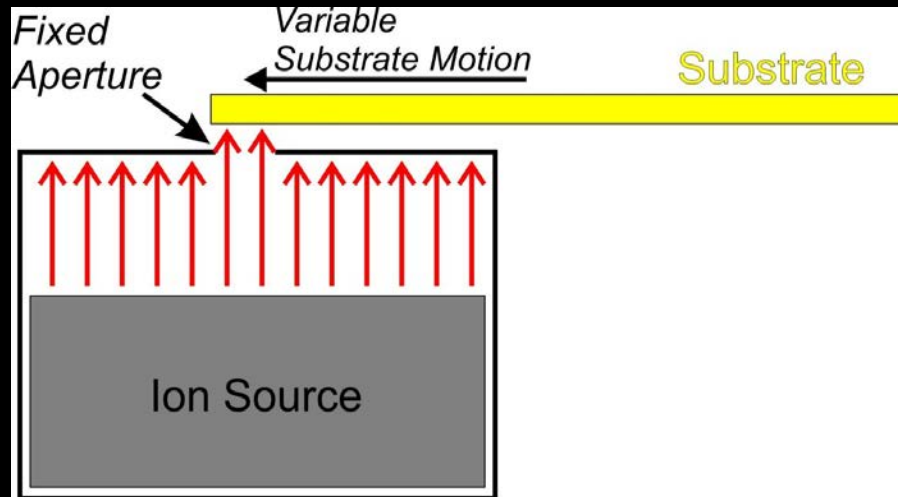
- Motivation and issues
- Categories of potential solutions
- **Post-fabrication corrections**
 - ❑ Differential erosion or deposition
 - ❑ Coating stress manipulation
 - ❑ Ion implantation

Low-pressure subtractive or additive machining corrects residual figure errors.

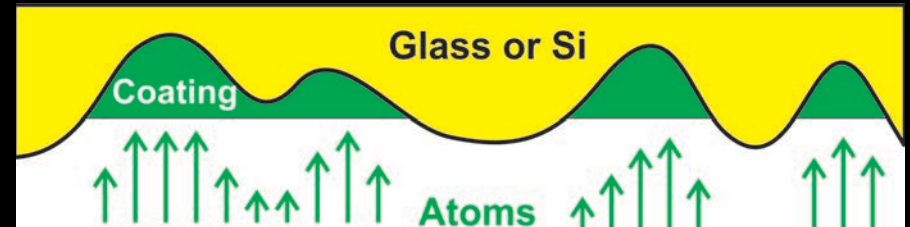
Differential Erosion



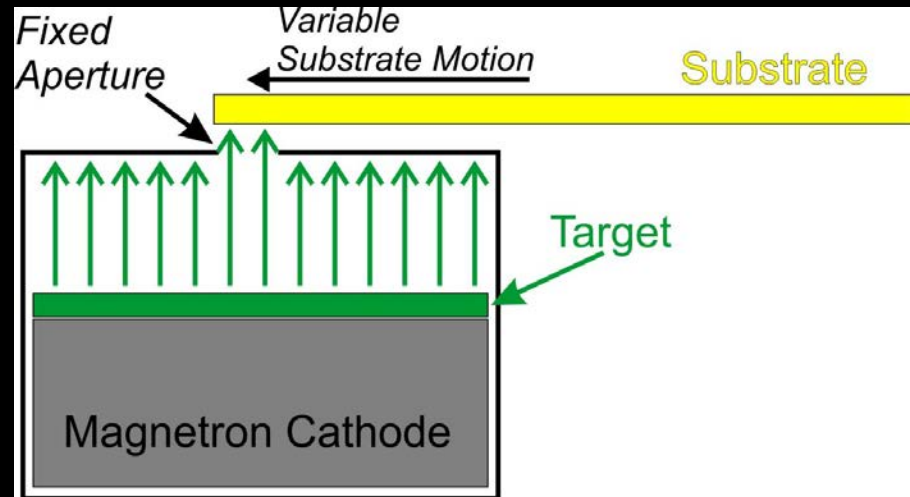
Ion-Beam Figuring



Differential Deposition

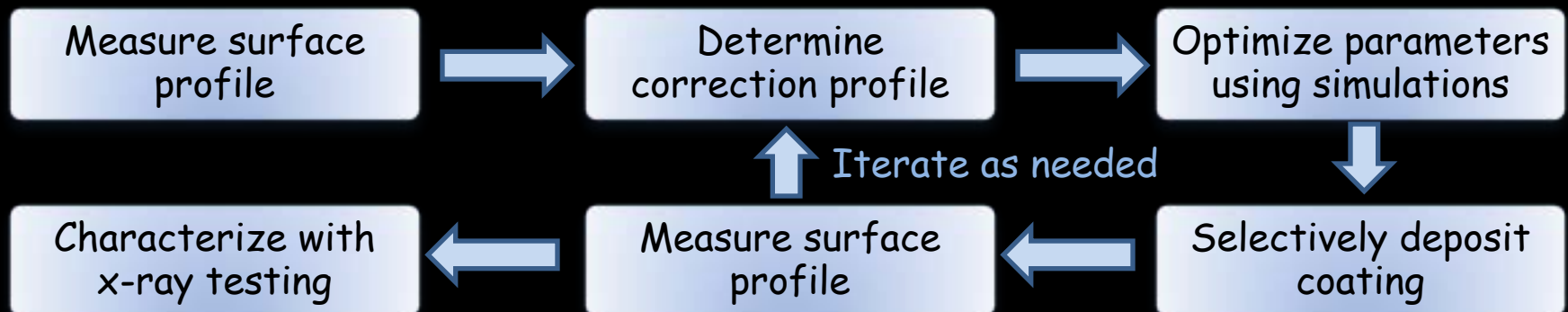
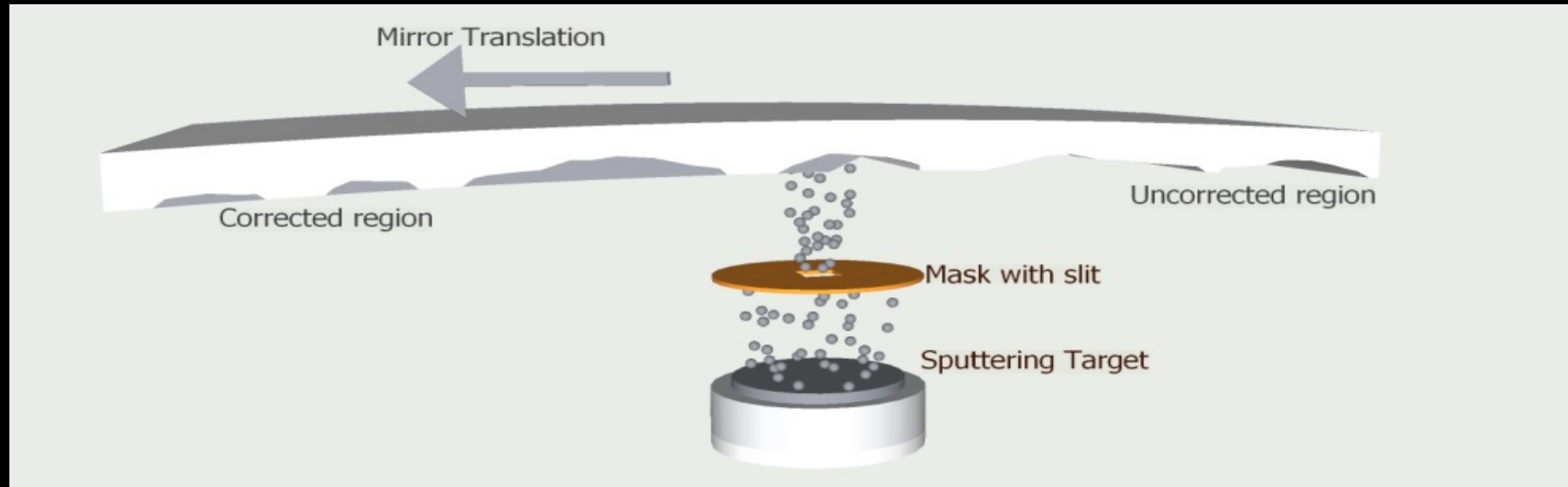


Selective Deposition



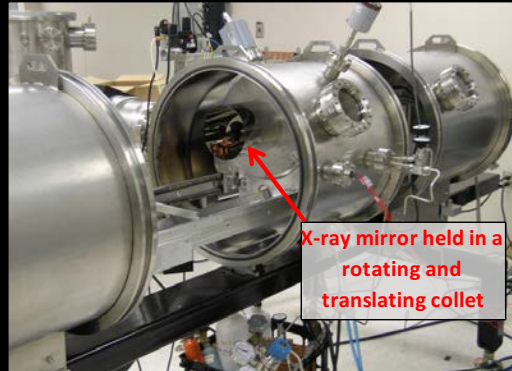
RXO/ David Windt

Differential deposition allows correction of mid-frequency figure errors.

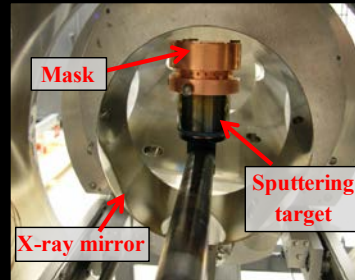


MSFC/USRA/ Kiran Kilaru

MSFC is applying differential deposition to correct thin-walled x-ray mirrors.

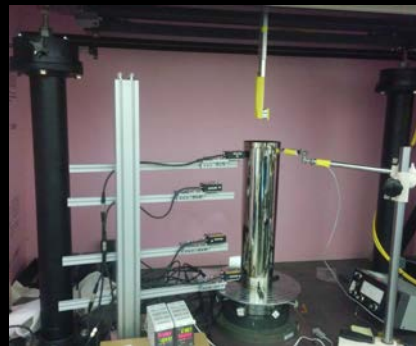


Horizontal differential-deposition chamber

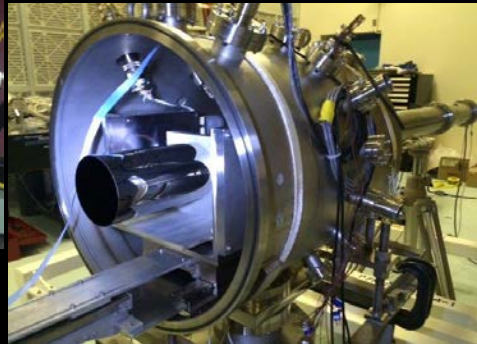


Sputtering head with copper mask positioned inside shell

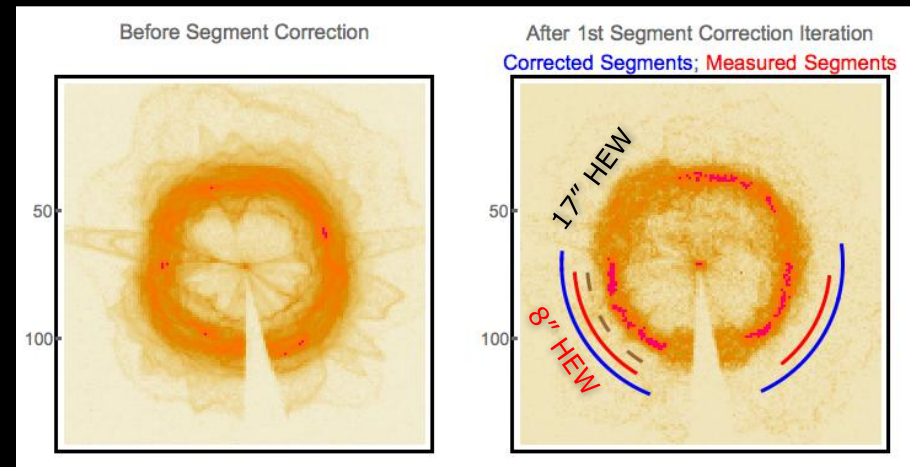
- Results are promising.
 - ❑ 2-pass correction of HEW by factor of 3 (metrology)
 - ❑ 1-pass correction of HEW by factor of 2 (x-ray test)
 - 3 corrected azimuthal sections in intrafocal image



Metrology of shell with MSFC VLTP and circularity test stand

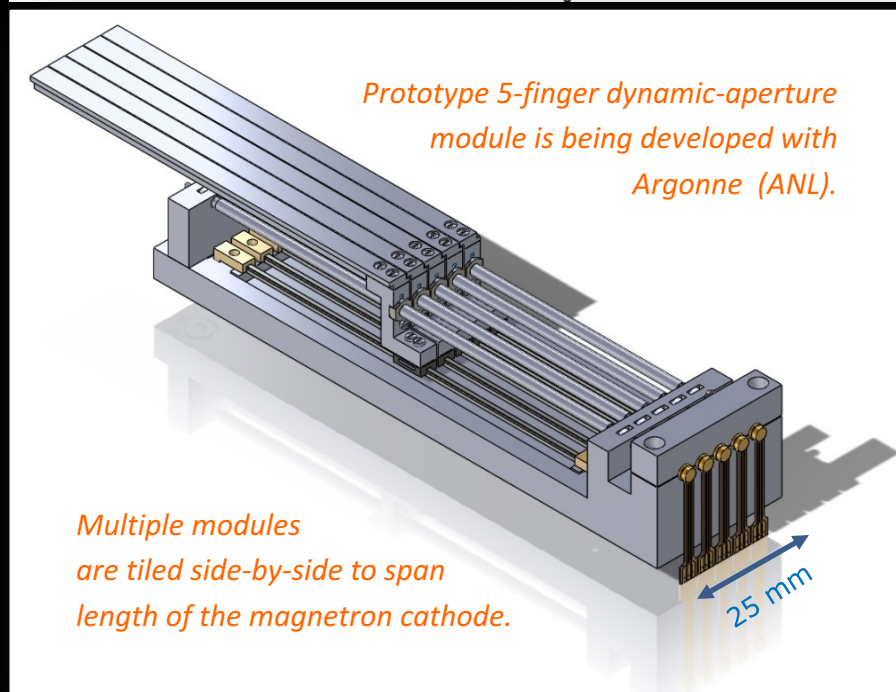
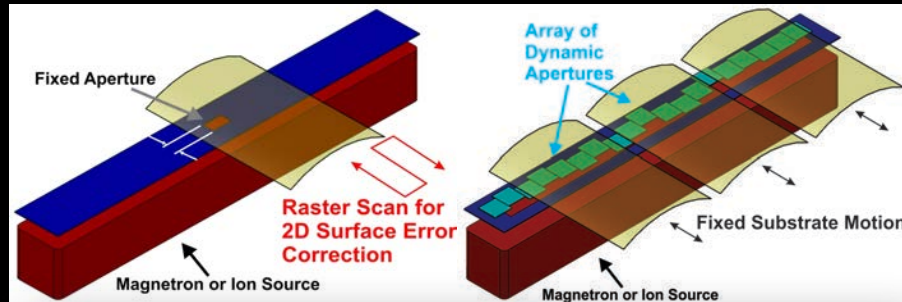


Corrected shell installed in bell housing for x-ray testing at MSFC 100-m beam

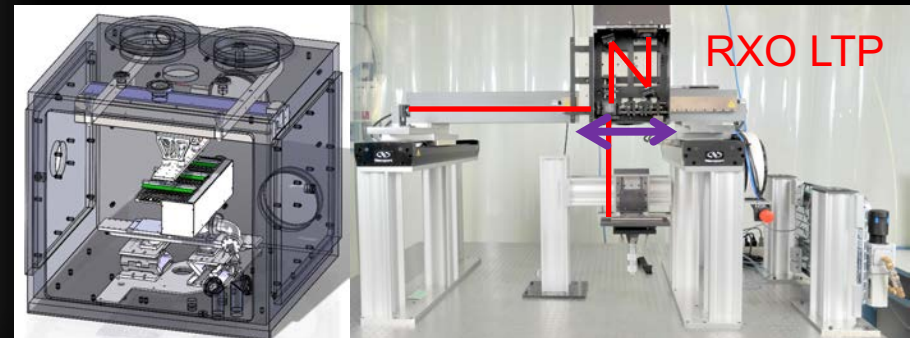


MSFC/USRA/ Kiran Kilaru

RXO is developing dynamic apertures for 2D differential erosion or deposition.



- Dynamic aperture array
 - ❑ Simultaneously corrects multiple azimuths
 - Constant axial speed
 - Modulated aperture widths
 - ❑ Applications
 - Differential erosion
 - Differential deposition
 - Laterally graded multilayer



RXO/ David Windt

Coating stress is an issue for sub-arcsecond imaging with thin mirrors.

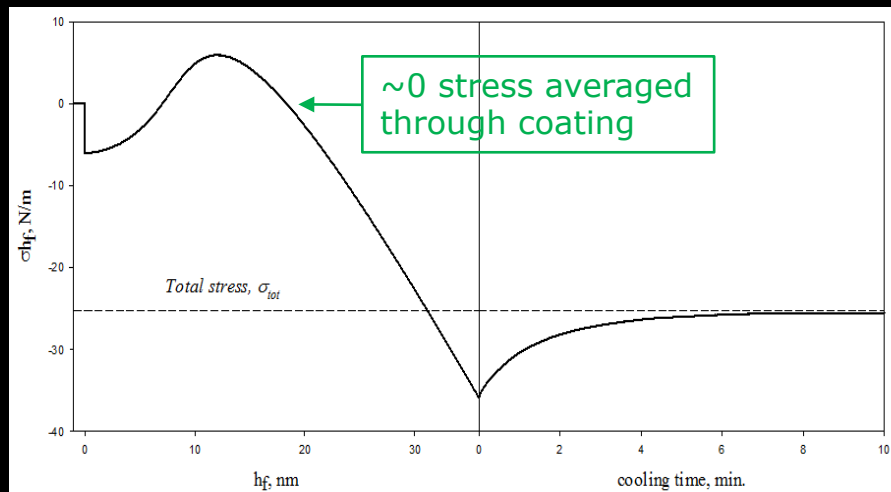
- Astronomical x-ray mirrors use thin-film coatings.
 - ❑ High-density coating or multilayers for x-ray reflectivity
 - ❑ For active optics, piezoelectric array
- Distortion depends upon film stress σ_f and thickness h_f and upon substrate thickness h_s .
 - ❑ E.g., Stoney formula: $\kappa = 6(1 - \nu_s)\sigma_f h_f / (E_s h_s^2)$
 - Dependence upon substrate thickness h_s is quadratic.
 - Key coating parameter is the integrated stress $\sigma_f h_f$.
 - ❑ Both intrinsic coating stress and temperature-dependent strain (CTE differences) cause distortion.
 - Separating these two effects can be challenging.
 - Annealing or other relaxation may play a role.

Several groups are investigating various methods for controlling coating stress.

- Monitor integrated stress in situ during sputtering, to take advantage of dynamics of thin-film growth.
 - ❑ MSFC/ David Broadway
- Deposit bilayer to tune the net integrated stress of compressive and tensile thin films.
 - ❑ RXO/ David Windt; SAO/ Suzanne Romaine
- Deposit coating on front and on back to balance integrated stress.
 - ❑ GSFC/ Kai-Wing Chan
- Anneal coating at elevated temperature to relieve stress.
 - ❑ GSFC/ Kai-Wing Chan

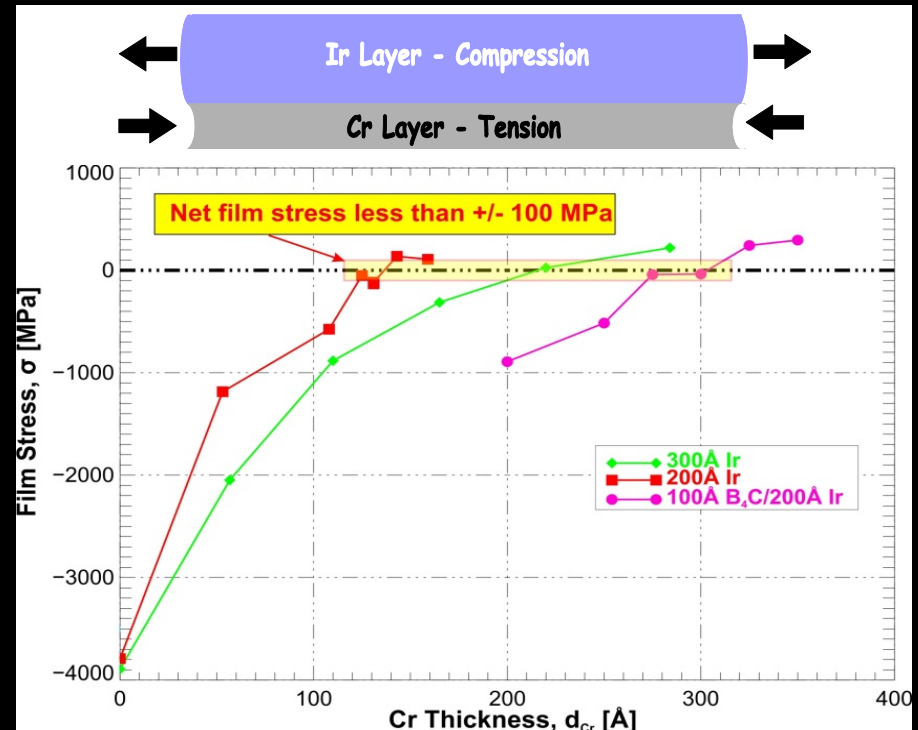
Methods for controlling deposition stress of thin films (continued)

- Iridium film growth
 - ❑ Tensile through coalescence stage
 - ❑ Very compressive after
- Tune mean stress of film
 - ❑ -3 MPa, 0.5-nm rough



MSFC/ David Broadway

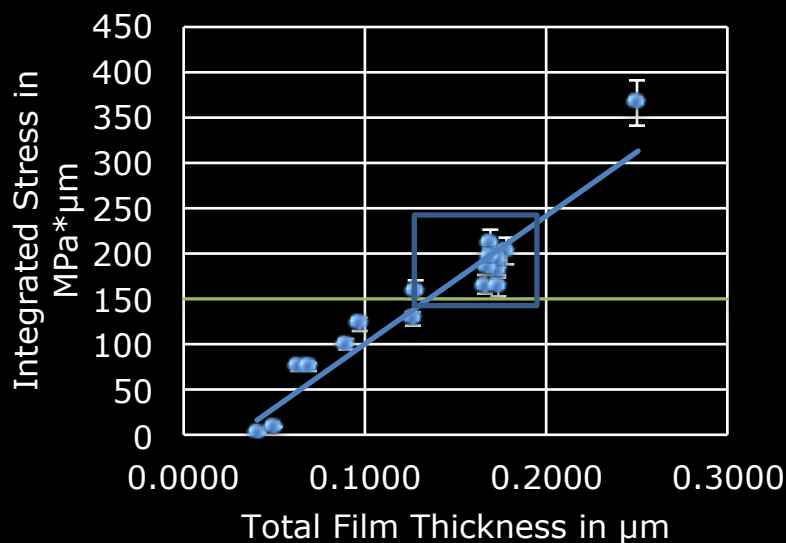
- Bilayer cancelation
 - ❑ Ir compressive stress
 - ❑ Cr tensile stress



RXO/ David Windt

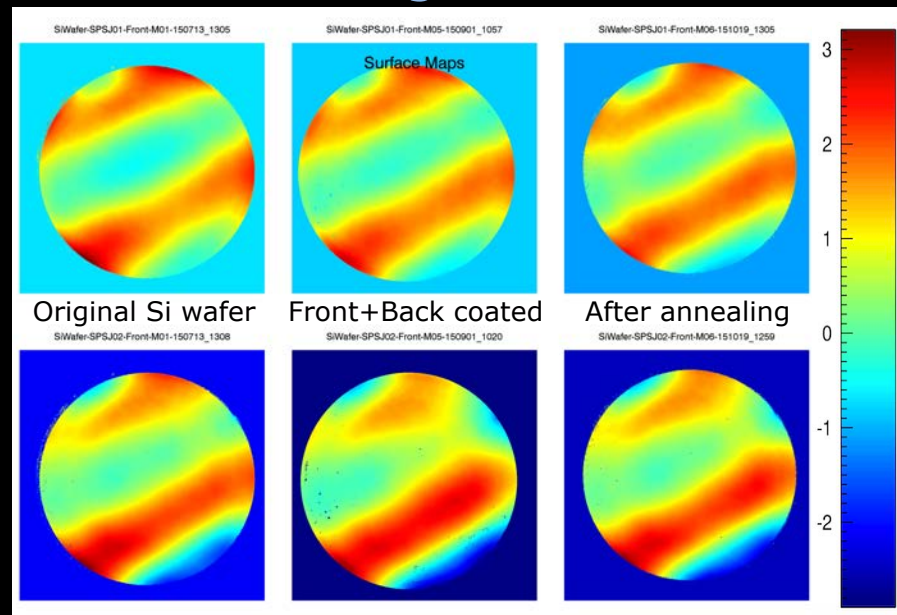
Methods for controlling deposition stress of thin films (continued)

- PZT compensation
 - ❑ PZT tensile stress on back
 - ❑ Ir/Cr bilayer on front
- Tune net integrated stress
 - ❑ 10-nm Ir + 160 nm Cr



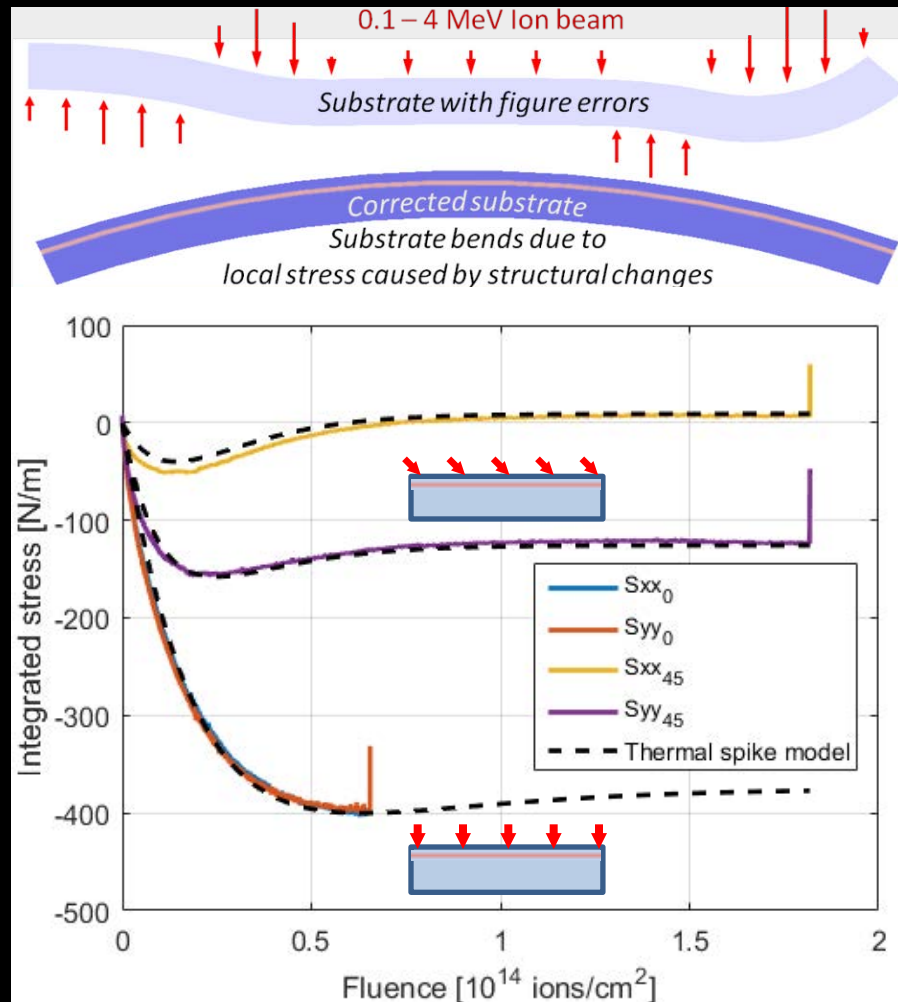
SAO/ Suzanne Romaine

- Multiple approaches
 - ❑ Front and back coating
 - Sputtering
 - Atomic Layer Deposition
 - ❑ Annealing at 320°C



GSFC/ Kai-Wing Chan

Differential stress from ion implantation allows static correction of figure errors.



- MIT is using its ion beam to develop this approach.
- ❑ Operates at 1-6 MeV.
 - Implant depth 1 – 4 μm
- ❑ Low surface degradation
- ❑ Integrated stress measure
 - Thermal spike model
 - Anisotropic (\parallel vs \perp) stress
 - Dose-dependent relaxation



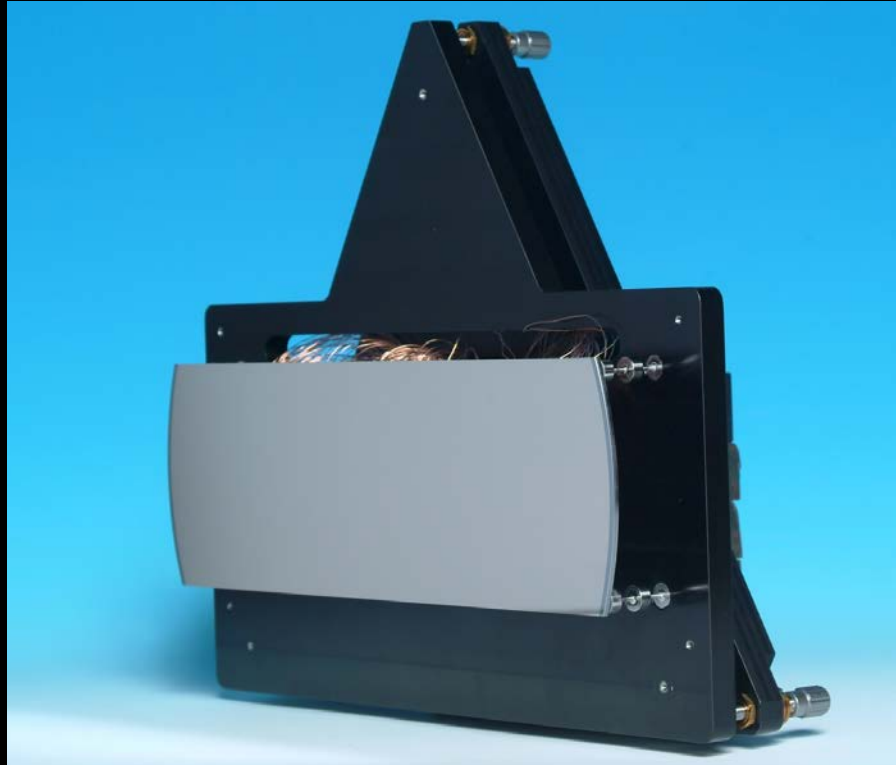
MIT/ Brandon Chalifoux

Outline

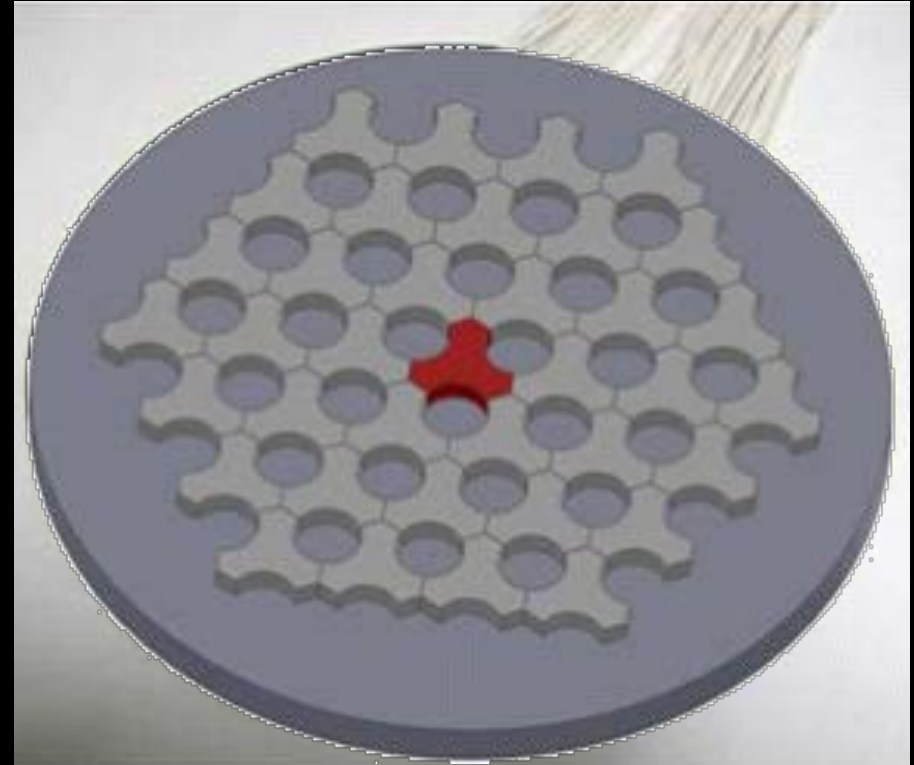
- Motivation and issues
- Categories of potential solutions
- Post-fabrication corrections

Back-up slides

An array of electroactive pads provides surface-tangential actuation (STA).



Xinetics deformable mirror (DM) uses 4×27 array of electrostrictive (PMN) pads bonded to mirror. Xinetics and ANL characterized DM.

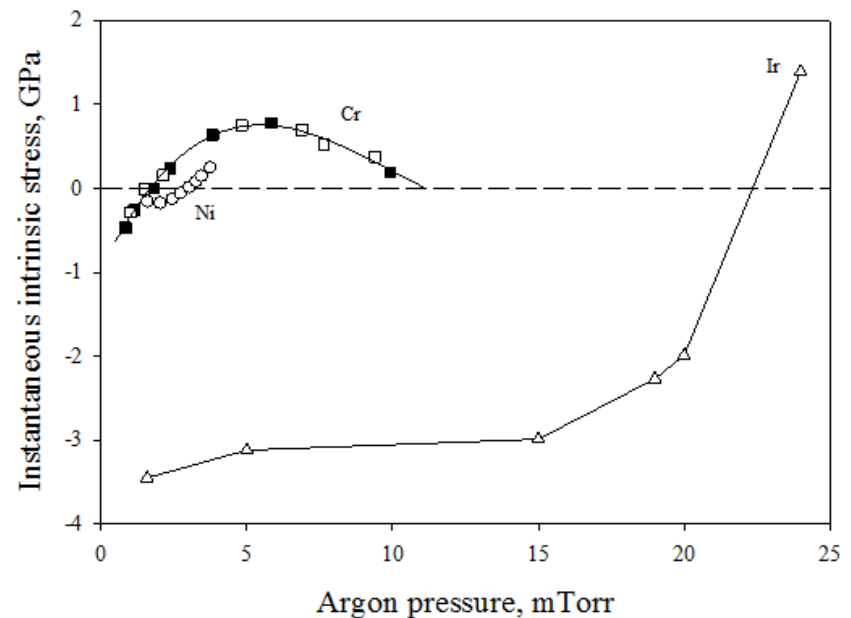
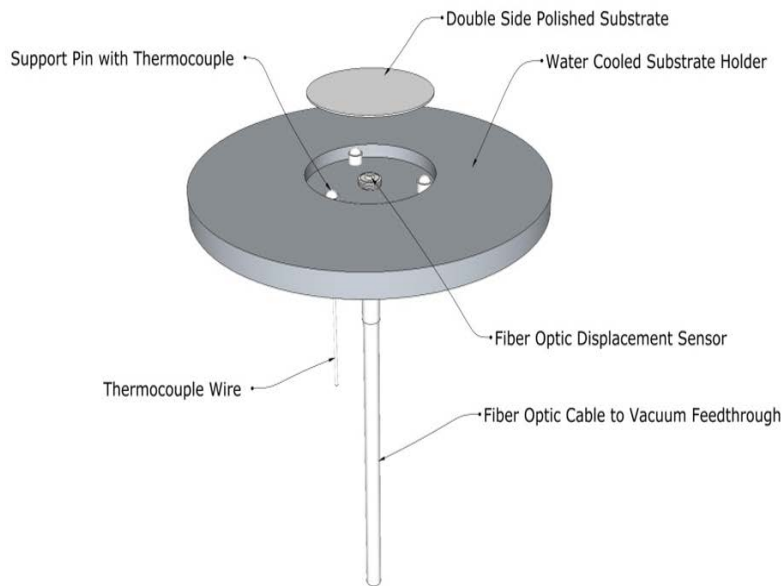


Xinetics prototype uses PMN array bonded to a silicon mirror. Each node is addressable for STA.

NGC/ AOA Xinetics

MSFC has developed thin-film-stress monitor for in situ measurements.

- In-situ measurement helped identify a mechanism for reducing the stress in sputtered iridium by 3 orders of magnitude



MSFC/ David Broadway